SYSTEM AND METHOD FOR HANDLING AND ALIGNING COMPONENT PANES SUCH AS FILM FRAMES AND WAFERS

Abstract

A system and method for transferring a component pane (e.g., semiconductor component such as a film frame or wafer) from a loading station to a vacuum table, the component pane being spatially aligned before placement thereof onto the vacuum table. The spatial alignment of the component pane can be completed, or substantially completed, prior to placement thereof onto the vacuum table. Accordingly, there is no need for the vacuum table to include alignment elements, means, or mechanisms. The system includes a first handler configured to transfer component panes from the loading station to an alignment station where spatial alignment of the component panes occurs, and a second handler configured to transfer the component panes from the alignment station to the vacuum table. The first handler includes a set of registration elements and the alignment station includes a set of alignment elements. The system is able to handle component panes of different sizes as well as different types of component panes (e.g., both film frames and wafers).

FIG. 1